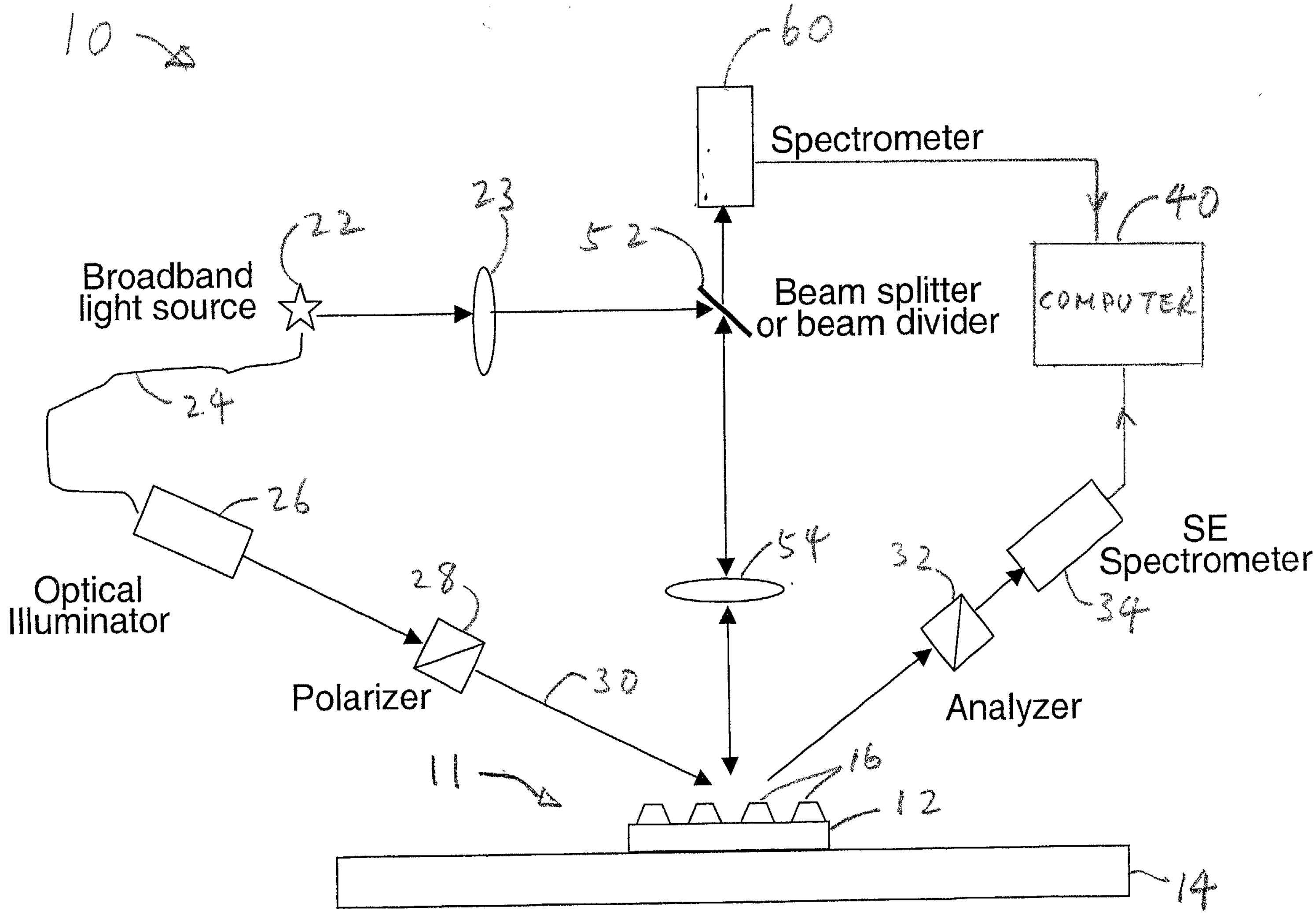


FIG. 1A

Light diffraction on grating

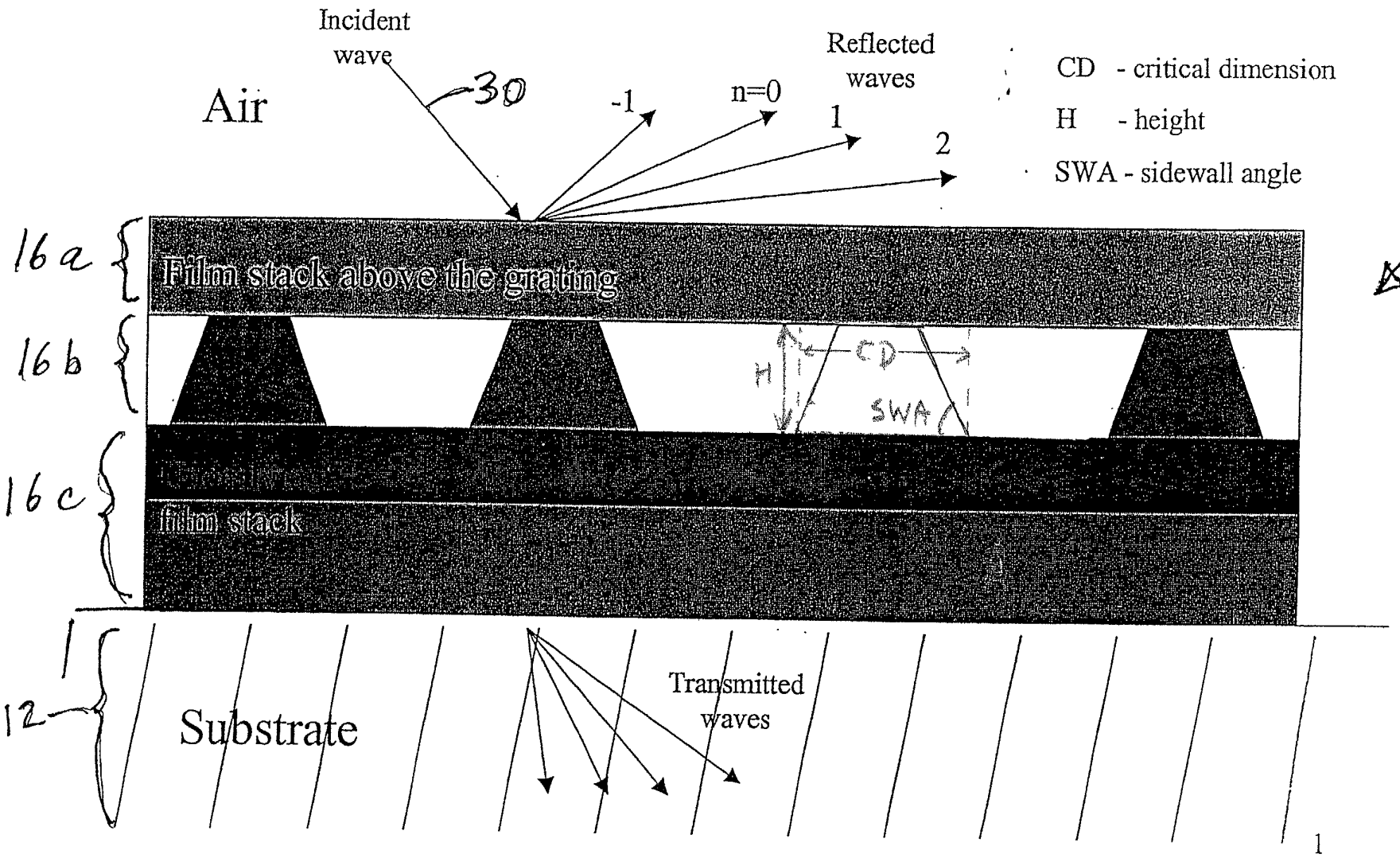


FIG. 1B

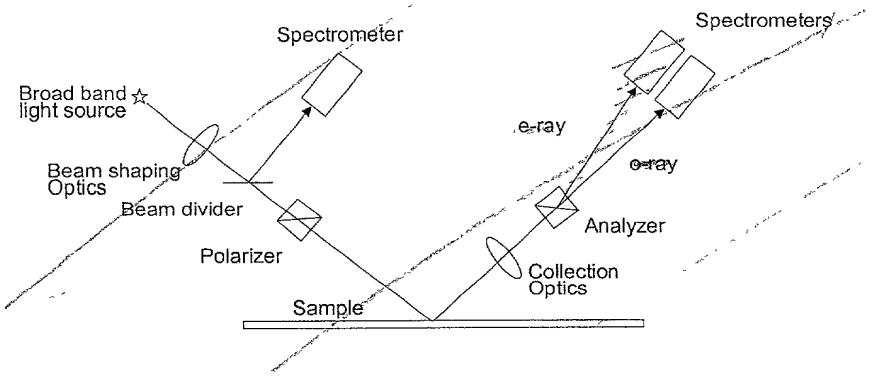


Figure 1

80

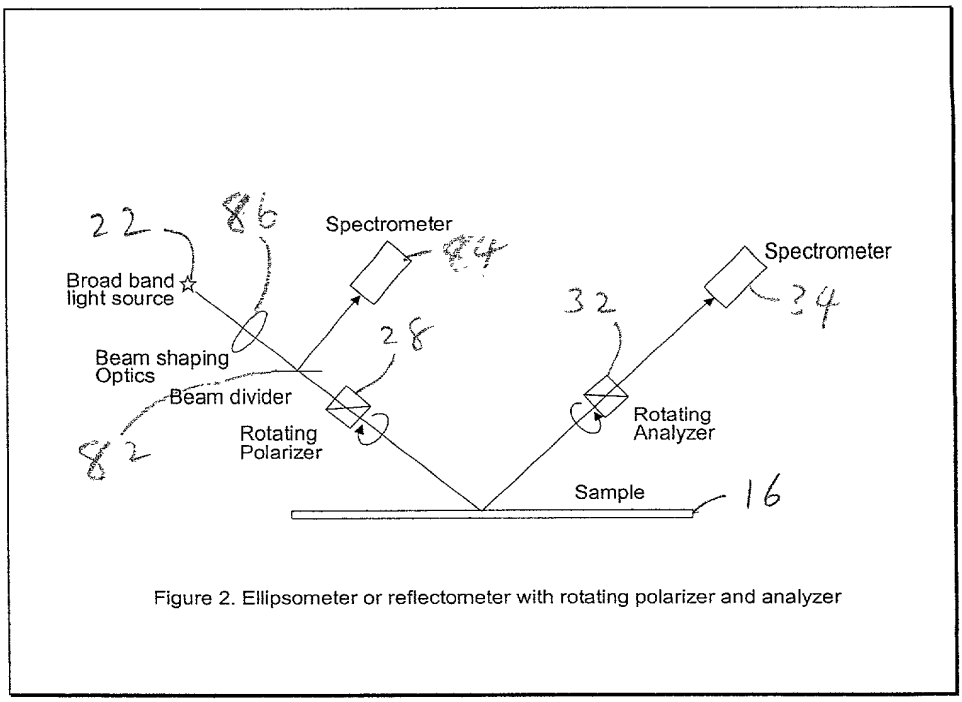


Figure 2. Ellipsometer or reflectometer with rotating polarizer and analyzer

~~Figure 3~~. Measured Structures (profile and film stack)

FIG. 3A

~~a.~~ Trapezoidal grating on top of a film stack

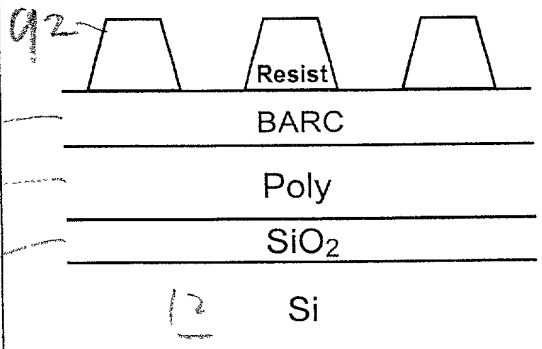
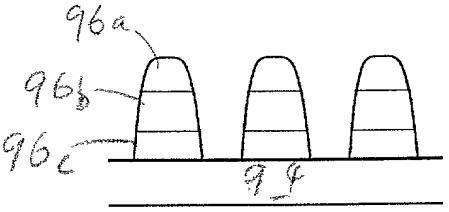


FIG. 3B

~~b.~~ Etched grating



~~c.~~ Grating with sidewall spacers

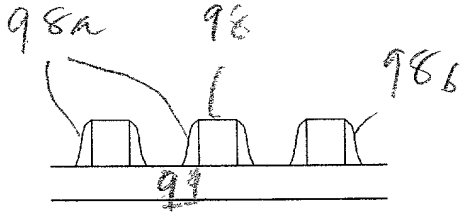


FIG. 3C

~~d.~~ Periodic structure with via holes

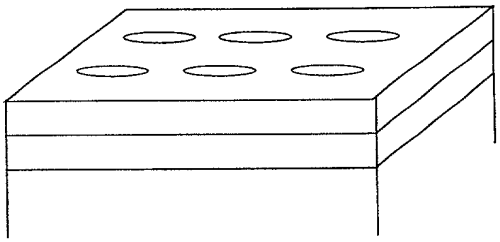


FIG. 3D

Figure 4: Sample Profile Models

Fig. 4A

a. Single material, multi-trapezoid profile

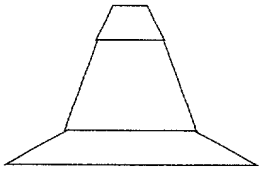
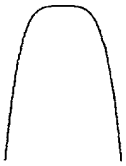


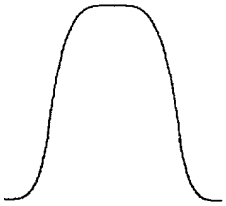
Fig. 4B

b. Single-material, quartic profile



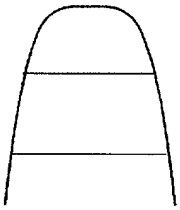
c. Single-material quartic profile with a bottom rounding

Fig. 4C



d. Multi-material etched profile based on the quartic model

Fig. 4D



e. Two-material profile with sidewall spacers

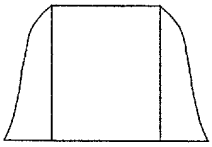


Fig. 4E

f. 3-dimensional via hole profile – a hole in a uniform layer

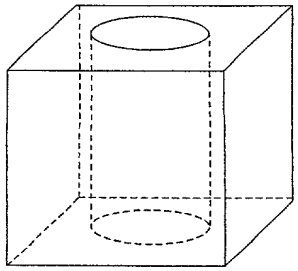


Fig. 4F

Figure 5. Flowchart of profile and film measurement

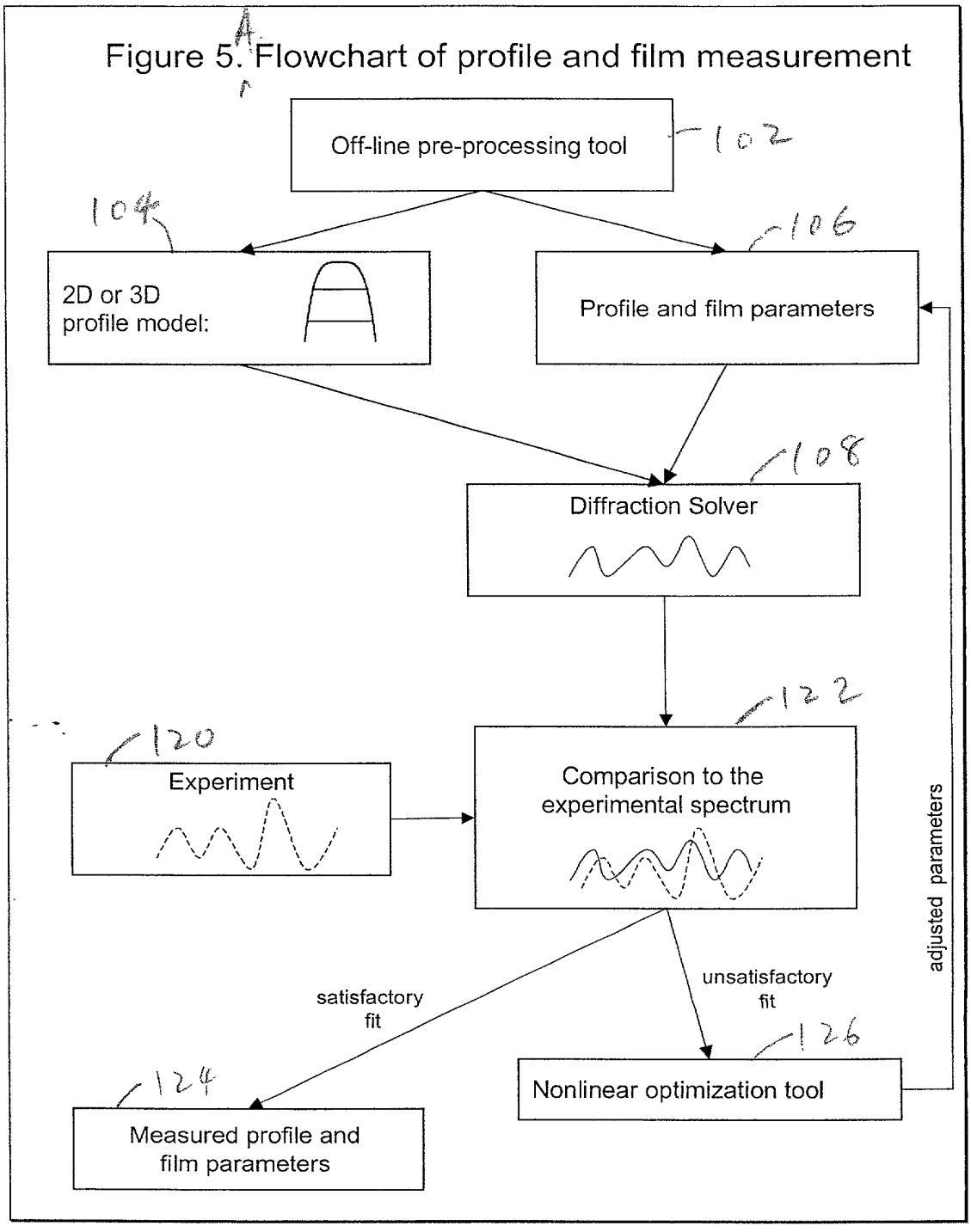


Figure 5a. Flowchart of Diffraction Solver

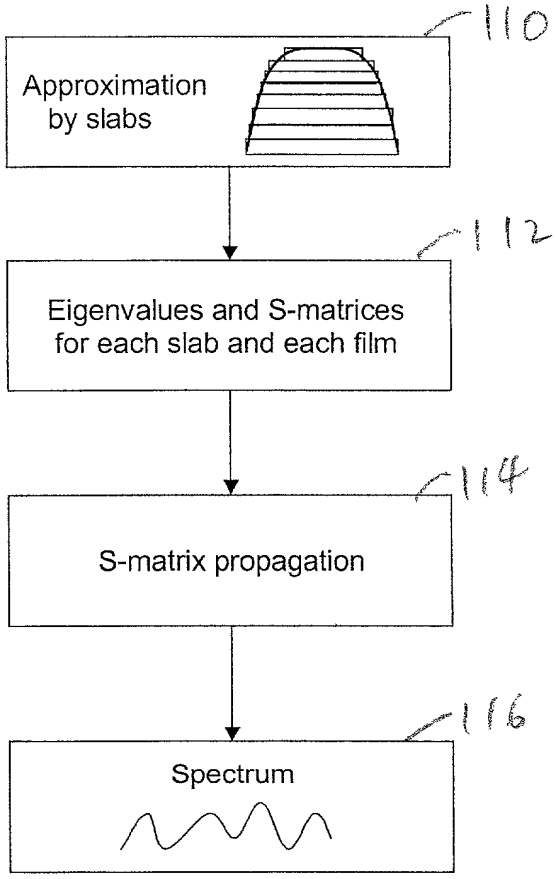


Figure 6a. Selection of the optimal profile model and initial seed

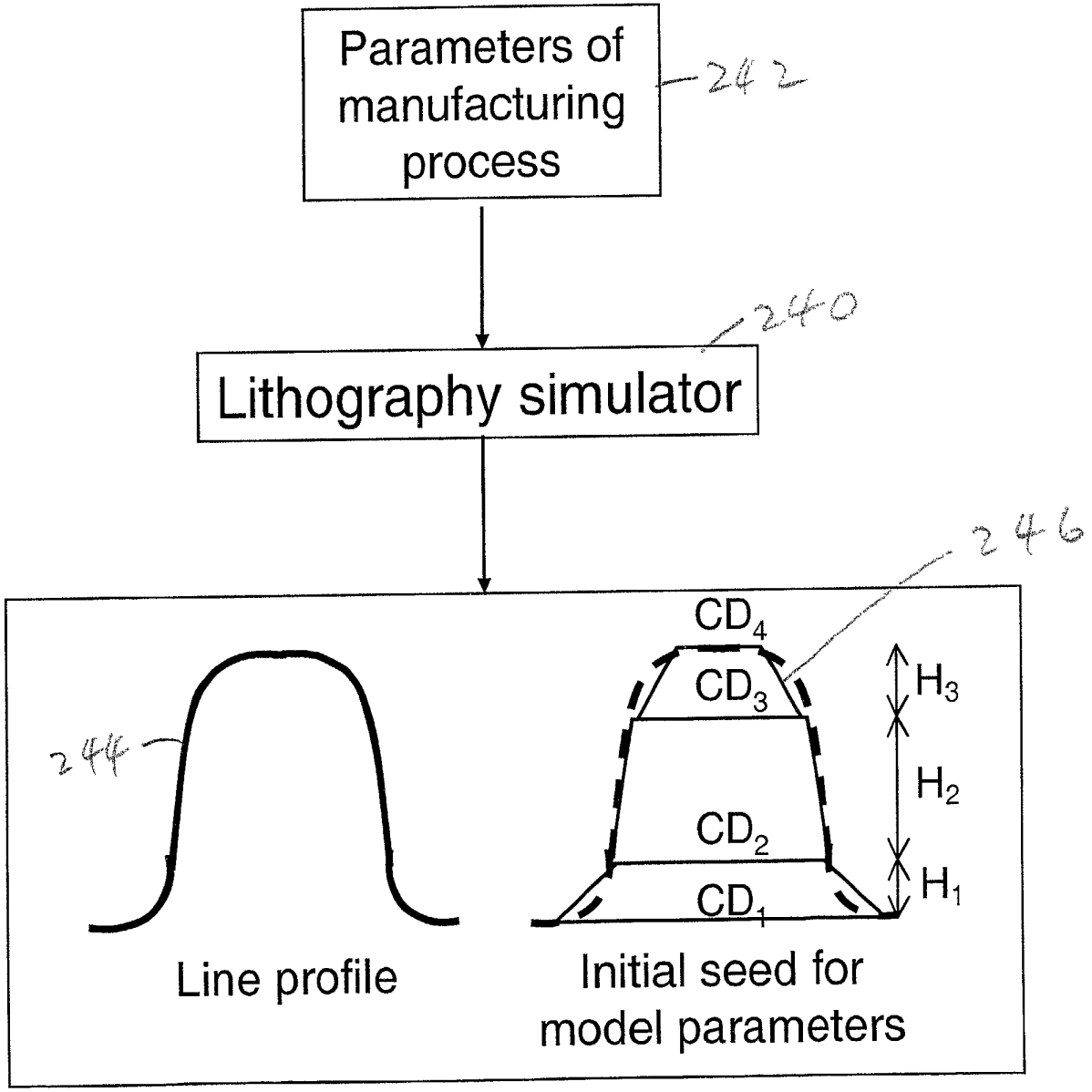
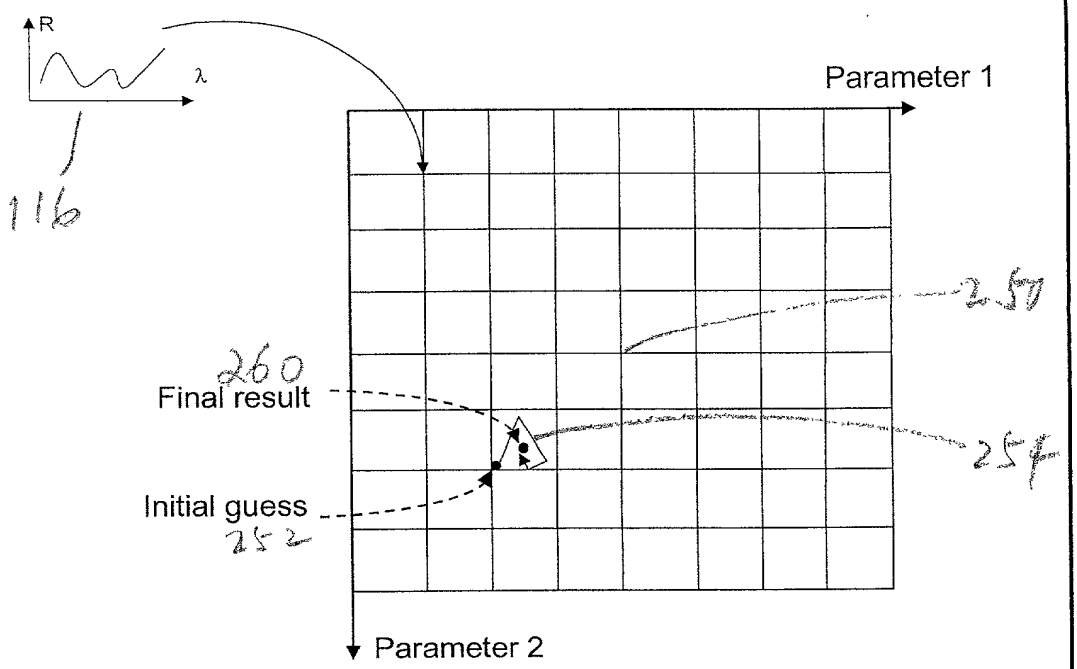
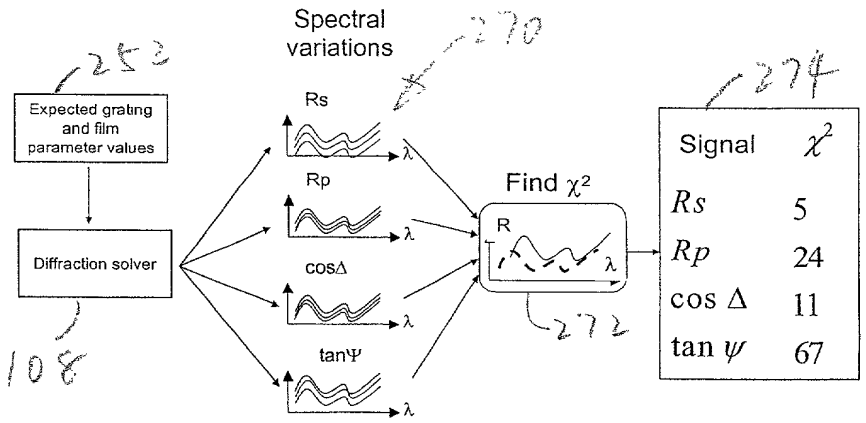


Figure 6c. Selection of the starting point for nonlinear optimization from the coarse library



6C

Figure 6b. Selection of the optimal signal for matching



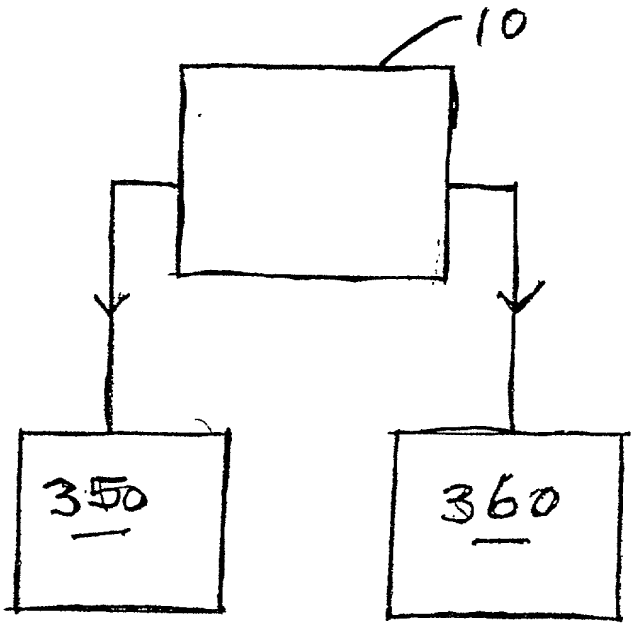
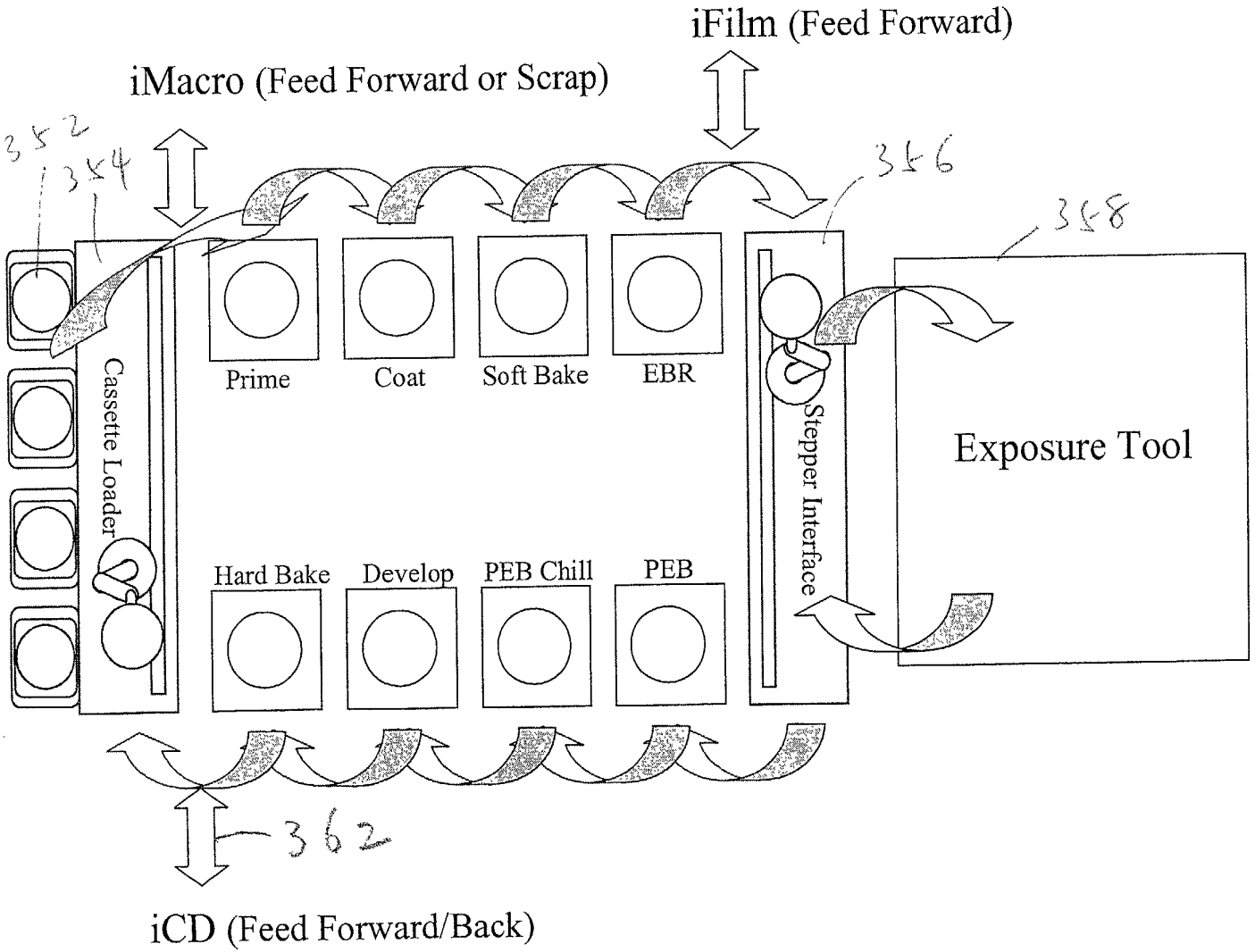


FIG. 12

FIG. 8

350

Points of Integration



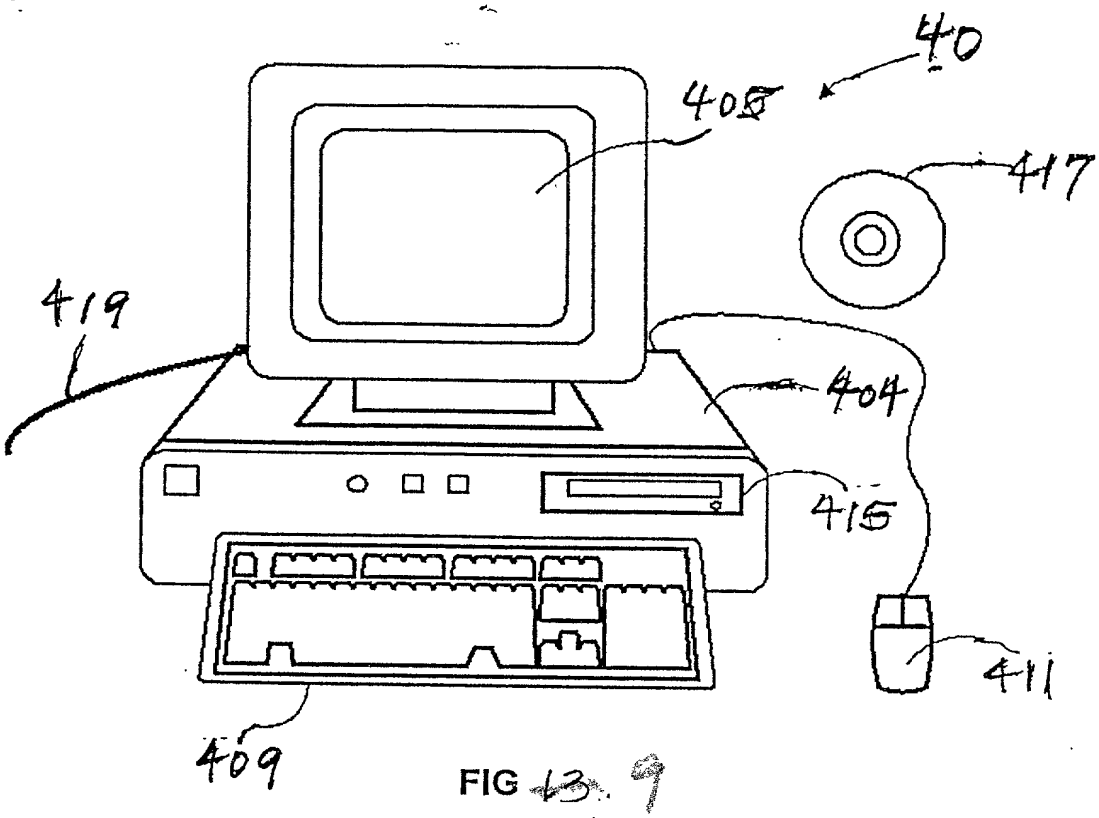


FIG 4B. 9